

## WHAT IS CLAIMED IS:

- 1 1. A method of correcting laser beam intensity, comprising
- 2 the steps of:
- 3 rotating an optical substrate around an optical axis
- 4 of a laser beam as a rotation axis while maintaining an
- 5 incident angle of the laser beam thereto, the optical
- 6 substrate being located in a manner that the incident angle
- 7 of the laser beam is set at a Brewster's angle; and
- 8 controlling transmission intensity of the laser beam.

- 1 2. A method of correcting laser beam intensity by using
- 2 laser beam intensity correcting mechanism including a
- 3 plurality of optical paths, a rotation cylinder being
- 4 rotated around an optical axis of the laser beam as a rotation
- 5 axis arranged in at least one of the plurality of optical
- 6 paths and an optical substrate fixed at a predetermined
- 7 slope angle with respect to the optical axis provided in
- 8 the rotation cylinder, comprising a step of:
- 9 rotating the rotation cylinder to rotate the optical
- 10 substrate around the optical axis as the rotation axis while
- 11 maintaining the slope angle.

- 1 3. The method of correcting laser beam intensity according
- 2 to claim 2, further comprising a step of:
- 3 adjusting the laser beam intensity in each optical
- 4 path to be equal to others.

1 4. A laser beam intensity correction mechanism including  
2 an optical substrate rotating around an optical axis of  
3 a laser beam as a rotation axis while maintaining an incident  
4 angle, the optical substrate being located in a manner that  
5 the incident angle of the laser beam is set at a Brewster's  
6 angle, wherein transmission intensity of the laser beam  
7 is varied by rotating the optical substrate.

1 5. A laser beam intensity correction mechanism according  
2 to claim 4, wherein the optical substrate is made of a quartz  
3 plate.

1 6. A laser beam intensity correction mechanism according  
2 to claim 4, wherein an antireflection coating is formed  
3 on at least one surface of the optical substrate.

1 7. A laser beam intensity correction mechanism comprising  
2 a rotation cylinder being rotated around an optical axis  
3 of a laser beam as a rotation axis and an optical substrate  
4 fixed at a predetermined slope angle with respect to the  
5 optical axis of the laser beam in the rotation cylinder,  
6 wherein the optical substrate is rotated around the optical  
7 axis as the rotation axis while maintaining the slope angle  
8 by rotating the rotation cylinder.

1 8. A laser beam intensity correction mechanism according

2 to claim 7, wherein the slope angle of the optical substrate  
 3 is set in a manner that the incident angle of the laser  
 4 beam is set at the Brewster's angle.

1 ~~3~~. A laser beam intensity correction mechanism comprising  
 2 a plurality of optical paths for a plurality of laser beams,  
 3 a rotation cylinder provided in at least one of the plurality  
 4 of optical paths, the rotation cylinder being rotated  
 5 around an optical axis of the laser beam as a rotation axis,  
 6 and an optical substrate fixed at a predetermined slope  
 7 angle with respect to the optical axis of the laser beam  
 8 provided in the rotation cylinder, wherein the optical  
 9 substrate is rotated around the optical axis as the rotation  
 10 axis while maintaining the slope angle by rotating the  
 11 rotation cylinder.

1 ~~4~~ 10. A laser beam intensity correction mechanism according  
 2 to claim ~~3~~, wherein the slope angle of the optical substrate  
 3 is set such that the incident angle of the laser beam is  
 4 set at the Brewster's angle.

1 ~~5~~ 11. A laser generating device comprising a laser beam  
 2 source, an optical part for splitting the laser beam emitted  
 3 from the laser beam source into a plurality of optical paths  
 4 and correcting means for correcting laser beam intensity,  
 5 the correcting means being provided in at least one of  
 6 the optical paths, wherein the correcting means includes

1 12. A laser generating device according to claim 11,  
2 wherein the correcting means is provided in an optical path  
3 except a reference optical path.